



2877

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Heaton, John D.; Spady, Blaine R.
Assignee: Nanometrics Incorporated
Title: Metrology/Inspection Positioning System
Serial No.: 09/458,123 Filing Date:
Examiner: Unknown Group Art Unit: 2877
Docket No.: M-7677 US

5 / IDS
10/3/00
S. Royall

San Jose, California
September 21, 2000

COMMISSIONER FOR PATENTS
WASHINGTON, D. C. 20231

INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR § 1.97(b)

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, the documents listed on the accompanying PTO Form-1449 are called to the attention of the Examiner for the above patent application. Copies of these documents are enclosed.

Citation of these documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant invention;
2. a representation that a search has been made; or
3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

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I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on September 21, 2000.

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9-21-00
Date of Signature

Respectfully submitted,

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